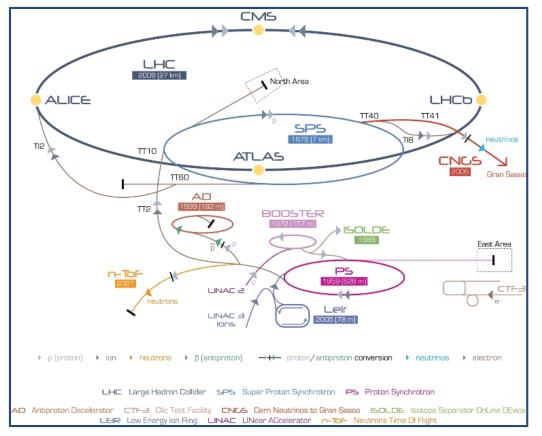




Gas Flow, Conductance, Pressure Profile: Vacuum Technology for Accelerators with Exercises

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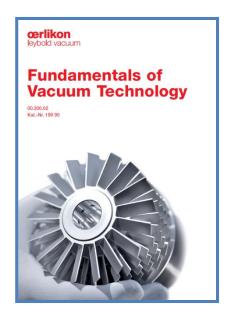
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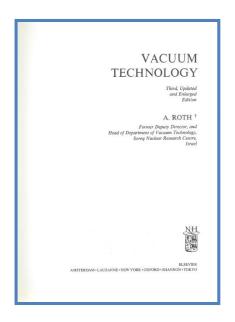
- Concepts of gas flow, conductance, pressure profile as relevant to the design of the vacuum system of modern accelerators;
 - A quick definition of the terms involved;
 - Some computational models and algorithms: analytical vs numerical;
 - Simple exercises
 - · Conclusions:
 - References to documents are given during presentation.

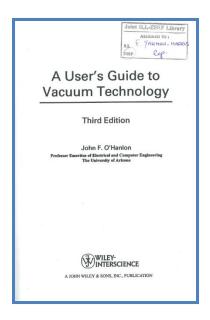
Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators

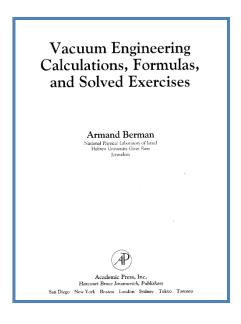
Sources: "[1] Fundamentals of Vacuum Technology", Oerlikon-Leybold (*); [2] "Vacuum Technology, A. Roth, Elsevier;

[3] "A User's Guide to Vacuum Technology", J.F. O'Hanlon, Wiley-Interscience;
[4] "Vacuum Engineering Calculations, Formulas, and Solved Exercises", A. Berman,
Academic Press;



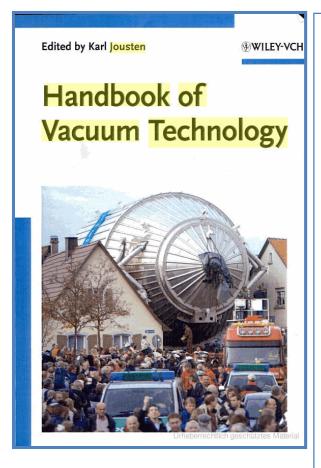






(*) Not endorsing products of any kind or brand

Sources: [5] "Handbook of Vacuum Technology", K. Jousten ed., Wiley-Vch, 1002 p.



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Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Units and Definitions [1]

Unit	N · m ⁻² , Pa ²⁾	mbar	bar	Torr
1 N · m ⁻² (= 1 Pa)	1	1 · 10 ⁻²	1 · 10 ⁻⁵	7.5 · 10 ⁻³
1 mbar	100	1	1 · 10 ⁻³	0.75
1 bar	1 · 10 ⁵	1 · 103	1	750
1 Torr ³⁾	133	1.33	1.33 · 10 ⁻³	1

- 1) The torr is included in the table only to facilitate the transition from this familiar unit to the statutory units N·m², mbar and bar. In future the pressure units torr, mm water column, mm mercury column (mm Hg), % vacuum, technical atmosphere (at), physicalatmosphere (atm), atmosphere absolute (ata), pressure above atmospheric and pressure below atmospheric may no longer be used. Reference is made to DIN 1314 in this context.
- 2) The unit Newton divided by square meters (N \cdot m⁻²) is also designated as Pascal (Pa): 1 N \cdot m⁻²= 1 Pa.
 - Newton divided by square meters or Pascal is the SI unit for the pressure of fluids.
- 3) 1 torr = 4/3 mbar; fl torr = 1 mbar.

Table I: Permissible pressure units including the torr 1) and its conversion

Abbrev.	Gas	$C^* = \lambda \cdot p$ [cm · mbar]
H ₂	Hydrogen	12.00 · 10 ⁻³
He	Helium	18.00 · 10 ^{−3}
Ne	Neon	12.30 · 10 ⁻³
Ar	Argon	6.40 · 10 ⁻³
Kr	Krypton	4.80 · 10 ^{−3}
Xe	Xenon	3.60 ⋅ 10 ⁻³
Hg	Mercury	$3.05 \cdot 10^{-3}$
O_2	Oxygen	6.50 · 10 ⁻³
N_2^2	Nitrogen	6.10 · 10 ⁻³
HČI	Hydrochloric acid	4.35 ⋅ 10 ⁻³
CO ₂	Carbon dioxide	3.95 · 10 ^{−3}
H ₂ Ó	Water vapor	3.95 · 10 ^{−3}
NH ₃	Ammonia	4.60 · 10 ^{−3}
C ₂ H ₅ OH	Ethanol	2.10 · 10 ⁻³
Cĺ ₂	Chlorine	$3.05 \cdot 10^{-3}$
Air	Air	6.67 · 10 ⁻³
Values	ree path I of the product c* of the mean free path λ (see also Fig. 9.1)	and pressure p for various gases

1 ↓ = →	mbar	Pa	dyn · cm ^{−2}	atm	Torr	inch	Micron	cm	kp · cm ^{−2}	lb · in⁻²	lb · ft⁻²
		(N/m ³)	(μbar)	(phys.)	(mm Hg)	Hg	(μ)	H ₂ O	(at tech.)	(psi)	
mbar	1	10 ²	10 ³	9.87 · 10 ⁻⁴	0.75	2.953 · 10 ⁻²	7.5 · 10 ²	1.02	1.02 · 10 ^{−3}	1.45 · 10 ⁻²	2.089
Pa	10 ⁻²	1	10	9.87 · 10 ⁻⁶	7.5 · 10 ⁻³	2.953 · 10 ⁻⁴	7.5	1.02 · 10 ⁻²	1.02 · 10 ⁻⁵	1.45 · 10 ⁻⁴	2.089 · 10 ⁻²
μbar	10 ⁻³	0.1	1	9.87 · 10 ⁻⁷	7.5 · 10 ⁻⁴	2.953 · 10 ⁻⁵	7.5 · 10 ⁻¹	1.02 · 10 ⁻³	1.02 · 10 ⁻⁶	1.45 · 10 ⁻⁵	2.089 · 10 ⁻³
atm	1013	1.01 · 10 ⁵	1.01 · 10 ⁶	1	760	29.92	7.6 · 10 ⁵	1.03 · 10 ³	1.033	14.697	2116.4
Torr	1.33	1.33 · 10 ²	1.33 · 10 ³	1.316 · 10 ⁻³	1	3.937 · 10 ⁻²	10 ³	1.3595	1.36 · 10 ⁻³	1.934 · 10 ⁻²	2.7847
in Hg	33.86	33.9 · 10 ²	33.9 · 10 ³	3.342 · 10 ⁻²	25.4	1	2.54 · 10 ⁴	34.53	3.453 · 10 ⁻²	0.48115	70.731
μ	1.33 · 10 ⁻³	1.33 · 10 ⁻¹	1.333	1.316 · 10 ⁻⁶	10 ⁻³	3.937 · 10 ⁻⁵	1	1.36 · 10 ⁻³	1.36 · 10 ⁻⁶	1.934 · 10 ⁻⁵	2.785 · 10 ⁻³
cm H ₂ O	0.9807	98.07	980.7	9.678 · 10 ⁻⁴	0.7356	2.896 · 10 ⁻²	7.36 · 10 ²	1	10 ^{−3}	1.422 · 10 ⁻²	2.0483
at	9.81 · 10 ²	9.81 · 10 ⁴	9.81 · 10 ⁵	0.968	7.36 · 10 ²	28.96	7.36 · 10 ⁵	103	1	14.22	2048.3
psi	68.95	68.95 · 10 ²	68.95 · 10 ³	6.804 · 10 ⁻²	51.71	2.036	51.71 · 10 ³	70.31	7.03 · 10 ⁻²	1	1.44 · 10 ²
lb · ft⁻²	0.4788	47.88	478.8	4.725 · 10 ⁻⁴	0. 3591	1.414 · 10 ⁻²	359.1	0.488	4.88 · 10 ⁻⁴	6.94 · 10 ⁻³	1

Normal conditions: 0 $^{\circ}$ C and sea level, i.e. p = 1013 mbar = 760 mm Hg = 760 torr = 1 atm

in Hg = inches of mercury; 1 mtorr (millitorr) = 10^{-3} torr = 1 μ (micron ... μ m Hg column)

Pounds per square inch = lb · in 2 = lb / sqin = psi (psig = psi gauge ... pressure above atmospheric, pressure gauge reading; psia = psi absolute ... absolute pressure)

Pounds per square foot = lb / sqft = lb / ft²; kgf/sqcm² = kg force per square cm = kp / cm² = at; analogously also: lbf / squin = psi

1 dyn \cdot cm⁻² (cgs) = 1 μ bar (microbar) = 1 barye; 1 bar = 0.1 Mpa; 1 cm water column (cm water column = g / cm² at 4 °C) = 1 Ger (Geryk)

atm ... physical atmosphere – at ... technical atmosphere; 100 - (x mbar / 10.13) = y % vacuum

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Units and Definitions [1]

• Without bothering Democritus, Aristotles, Pascal, Torricelli et al... a <u>modern</u> definition of "vacuum" is the following (American Vacuum Society, 1958):

"Given space or volume filled with gas at pressures below atmospheric, i.e. less than 2.5E+19 molecules/cm³"

• Keeping this in mind, the following curve [2] defines the molecular density vs pressure and the mean free path (MFP), a very important quantity:

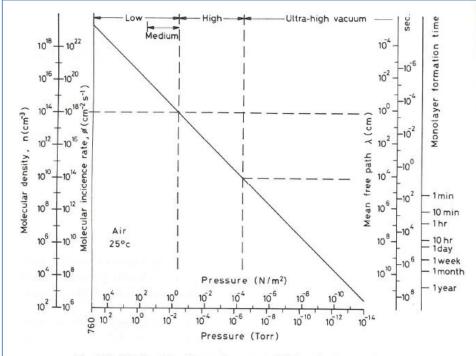


Fig. 1.1 Relationship of several concepts defining the degree of vacuum.

Mean-free path: average distance travelled by a molecule before hitting another one (ternary, and higher-order, collisions are negligible)

The importance of obtaining a low pressure, in accelerators, is evident:

- reduce collisions between the particle beams and the residual gas;
- increase beam lifetime;
- reduce losses:
- reduce activation of components;
- reduce doses to experimenters;
- decrease number of injection cycles;
- improve beam up-time statistics;more..

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Units and Definitions

· A different view can be found here... http://hyperphysics.phyastr.gsu.edu/hbase/kinetic/menfre.html

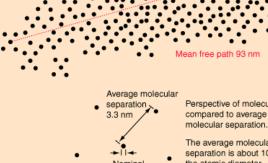
Mean Free Path Perspective

You may be surprised by the length of the mean free path compared to the average molecular separation in an ideal gas. An atomic size of 0.3 nm was assumed to calculate the other distances.

Model of an ideal gas at STP (760 mmHg pressure, 0°C)

The mean free path is 310 times the nominal atomic diameter and 28 times the average molecular separation.

Perspective of mean free path compared to average molecular separation. (Individual molecules are exaggerated in size by



0.3 nm

Perspective of molecular size compared to average

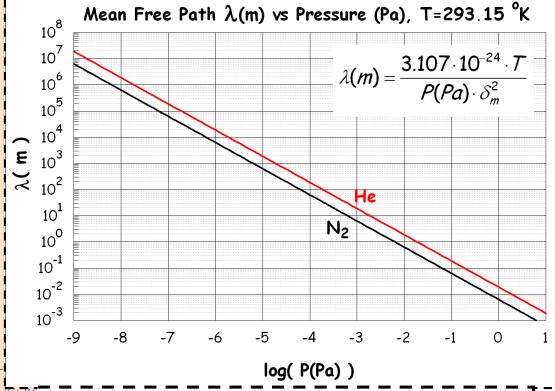
The average molecular separation is about 10x the atomic diameter

Mean Free Path Calculation Frequency of collision

HyperPhysics***** Thermodynamics

Nave

Gas	λ· p (m·Pa)	Gas	λ· p (m·Pa)
H ₂	11.5x10 ⁻³	CO ₂	4.0x10 ⁻³
N ₂	5.9x10 ⁻³	Ar	6.4x10 ⁻³
Не	17.5x10 ⁻³	Ne	12.7x10 ⁻³
СО	6.0x10 ⁻³	Kr	4.9x10 ⁻³



More molecular dimensions, δ_m , can be found here: http://www.kayelaby.npl.co.uk/general_physics/2_2/2_2_4.html

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Units and Definitions [5]

Definition of "flow regime"

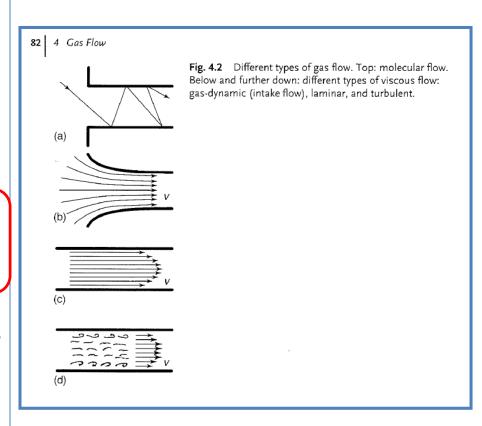
The so-called "Knudsen number" is defined as this:

$$Kn = \frac{\lambda}{D}$$

And the different flow (pressure) regimes are identified as follows:

FREE MOLECULAR FLOW : Kn >1
TRANSITIONAL FLOW : 0.01 < Kn < 1
CONTINUUM (VISCOUS) FLOW: Kn < 0.01

Most accelerators work in <u>the free-molecular regime</u> i.e. in a condition where the MFP is bigger than the "typical" dimension of the vacuum chamber, and therefore molecular collisions can be neglected.



Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Units and Definitions

Definition of "vacuum ranges"

·Linked to the Knudsen number and the flow regimes, historically defined as in table

below [1];

		Rough vacuum	Medium vacuum	High vacuum	Ultrahigh vacuum
Pressure Particle number density Mean free path Impingement rate Volrelated collision rate Monolayer time Type of gas flow	$p \ [mbar]$ $n \ [cm^{-3}]$ $\lambda \ [cm]$ $Z_a \ [cm^{-2} \cdot s^{-1}]$ $Z_V \ [cm^{-3} \cdot s^{-1}]$ $\tau \ [s]$	$1013 - 1$ $10^{19} - 10^{16}$ $< 10^{-2}$ $10^{23} - 10^{20}$ $10^{29} - 10^{23}$ $< 10^{-5}$ Viscous flow	$\begin{array}{cccccccccccccccccccccccccccccccccccc$	$10^{-3} - 10^{-7}$ $10^{13} - 10^{9}$ $10 - 10^{5}$ $10^{17} - 10^{13}$ $10^{17} - 10^{9}$ $10^{-2} - 100$ Molecular flow	$< 10^{-7}$ $< 10^9$ $> 10^5$ $< 10^{13}$ $< 10^9$ > 100 Molecular flow
Other special features		Convection dependent on pressure	Significant change in thermal conductivity of a gas	Significant reduction- in volume related collision rate	Particles on the surfaces dominate to a great extend in relation to particles in gaseous space

With the advent of very low-outgassing materials and treatments (e.g. NEG-coating), "Ultrahigh vacuum" (UHV) is sometimes split up in "UHV" and "XHV" (eXtreme High Vacuum) regimes

Table 4 Classification of vacuum ranges [8].

Vacuum Ranges		Pressure Units				
		P	'a	mbar		
		min	max	min	max	
Low	(LV)	3.3×10^{3}	1.0×10^{5}	3.3 × 10	1.0×10^{3}	
Medium	(MV)	1.0×10^{-1}	3.3×10^{3}	1.0×10^{-3}	3.3 × 10	
High	(HV)	1.0×10^{-4}	1.0×10^{-1}	1.0×10^{-6}	1.0×10^{-3}	
Very High	(VHV)	1.0×10^{-7}	1.0×10^{-4}	1.0×10^{-9}	1.0 × 10 ⁻⁶	
Ultra-High	(UHV)	1.0×10^{-10}	1.0×10^{-7}	1.0×10^{-12}	1.0×10^{-9}	
Extreme		$\leq 1.0 \times 10^{-10}$		$\leq 1.0 \times 10^{-12}$		
Ultra-High	(XHV)					

• (Ref. N. Marquardt, CERN CAS)

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators

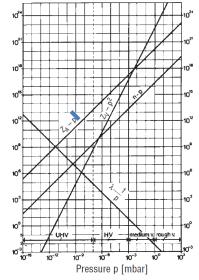
Impingement and Collision rates, and Ideal Gas Law

Impingement rate and collision rates

VARIABLE	General formula	For easy calculation	Value for air at 20 °C
Most probable speed of particles c _w	$c_W = \sqrt{\frac{2 \cdot R \cdot T}{M}}$	$c_W = 1.29 \cdot 10^4 \sqrt{\frac{T}{M}} \left[\frac{cm}{s} \right]$	c _w = 410 [m/s]
Mean velocity of particles \overline{c}	$\overline{c} = \sqrt{\frac{8 \cdot R \cdot T}{\pi \cdot M}}$	$\overline{c} = 1.46 \cdot 10^4 \sqrt{\frac{T}{M}} \left[\frac{cm}{s} \right]$	で = 464 [m/s]
Mean square of velocity of particles \overline{c}^2	$\overline{c}^2 = \frac{3 \cdot R \cdot T}{M}$	$\overline{C}^2 = 2.49 \cdot 10^8 \frac{T}{M} \left[\frac{cm^2}{s^2} \right]$	$\overline{c}^2 = 25.16 \cdot 10^4 \left[\frac{cm^2}{s^2} \right]$
Gas pressure p of particles	$p = n \cdot k \cdot T$ $p = \frac{1}{3} \cdot n \cdot m_T \cdot \overline{c}^2$ $p = \frac{1}{3} \cdot \hat{*} \cdot \overline{c}^2$	p = 13.80 · 10 ⁻²⁰ · n · T [mbar]	p = $4.04 \cdot 10^{-17} \cdot n$ [mbar] (applies to all gases)
Number density of particles n	n = p/kT	n = 7.25 · 10 ¹⁸ T [cm ⁻⁹]	p = 2.5 · 10 ¹⁶ · p [cm ⁻³] (applies to all gases)
Area-related impingement Z _A	$\begin{split} &Z_A \Rightarrow \frac{1}{4} \cdot n \cdot \overline{c} \\ &Z_A = \sqrt{\frac{N_A}{2 \cdot \pi \cdot M \cdot k \cdot T}} p \end{split}$	$Z_A = 2.63 \cdot 10^{22} \frac{p}{\sqrt{M \cdot T}} \cdot p \text{ [cm}^{-2} \text{ s}^{-1}]$	$Z_{A} = 2.85 \cdot 10^{20} \cdot p \text{ [cm}^{-2} \text{ s}^{-1}] \text{ (see Fig. 78.2)}$
Volume collision rate Z _V	$\begin{split} Z_V = & \frac{1}{2} \frac{n \cdot \overline{c}}{\lambda} \\ Z_A = & \frac{1}{c^2} \sqrt{\frac{2 \cdot N_A}{\pi \cdot M \cdot k \cdot T}} \rho^2 \end{split}$	$Z_V = 5.27 \cdot 10^{22} \frac{p^2}{c^* \cdot \sqrt{M \cdot T}} \text{ [cm}^{-3} \text{ s}^{-1}]$	$Z_V = 8.6 \cdot 10^{22} \cdot p^2 \text{ [cm}^{-3} \text{ s}^{-1}\text{] (see Fig. 78.2)}$
Equation of state of ideal gas	$p\cdot V=\nu\cdot R\cdot T$	p · V = 83.14 · v · T [mbar · `]	$p \cdot V = 2.44 \cdot 10^4 \text{ v [mbar · ~] (for all gases)}$
Area-related mass flow rate q _m , A	$q_{m, A} = Z_A \cdot m_T = \sqrt{\frac{M}{2 \cdot \pi \cdot k \cdot T \cdot N_A}} p$	$Q_{m, A} = 4.377 \cdot 10^{-2} \sqrt{\frac{M}{T}} \cdot p [g cm^{-2} s^{-1}]$	q _{m, A} = 1.38 · 10 ⁻² · p g [cm ⁻² s ⁻¹]

 $c^* = \lambda \cdot p$ in cm · mbar (see Tab. III) k Boltzmann constant in mbar · I · K⁻¹ λ mean free path in cm

Table IV: Compilation of important formulas pertaining to the kine



: mean free path in cm $(\lambda \sim 1/p)$

: particle number density in cm $^{-3}$ (n ~ p)

 Z_A : area-related impingement rate in cm⁻³ · s⁻¹ ($Z_A \sim p^{-1}$) : volume-related collision rate in cm⁻³ · s⁻¹ ($Z_V \sim p^2$)

Fig. 9.2: Diagram of kinetics of gases for air at 20 °C

• The <u>ideal gas law</u> states that the pressure P of a diluted gas is given by

$$PV = \frac{m}{M}RT = n_{M}RT = n_{M}N_{A}k_{B}T$$

... where:

 $V = volume, m^3; m = mass of gas, kg$

M = molecular mass, kg/mole

T = absolute temperature, °K

R = gas constant = 8.31451 J/mol/K

 n_M = number of moles

 N_A = Avogadro's number = 6.022E+23 molecules/mole

k_B = Boltzmann's constant = 1.381E-23 J/K

 Deviation from this law are taken care of by introducing higher-order terms...

$$PV = RT(1 + BP + CP^2 + \dots)$$

... which are not discussed here.

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators

Volumetric Flow Rate - Throughput - Basic Equations - Conductance

How does all this translates into "accelerator vacuum"?

 Let's imagine the simplest vacuum sistem, a straight tube with constant cross-section <u>connecting</u> two <u>large</u> <u>volumes</u>, P₁>P₂

$$Q = P \cdot dV/dt$$

Q, which has the units of

$$[Pa \cdot m^3/s] = [N \cdot m / s] = [J/s] = [W]$$

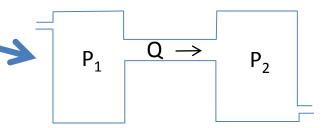
... is called the *throughput*. Therefore the throughput is <u>the power carried by a gas flowing out (or in) of the volume V at a rate of dV/dt.</u>

- dV/dt is also called "<u>volumetric</u>
 <u>flow rate</u>", and when applied to the
 inlet of a pump, it is called "<u>pumping</u>
 <u>speed</u>".
- Therefore, we can also write the <u>first basic equation</u> of vacuum technology

$$Q = P \cdot S$$

 Having defined the throughput, we move now to the concept of conductance, C:

Suppose we have two volumes V_1 and V_2 , at pressures $P_1 > P_2$ respectively, connected via a tube



...we can define a <u>second basic</u> <u>equation</u> of vacuum technology

$$Q = C \cdot (P_1 - P_2) = C \cdot \Delta P$$

... which, making an electrical analogy...

... gives an obvious interpretation of C as the reciprocal of a resistance to flow.

The higher the conductance the more "current" (throughput) runs through the system.

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Units and Definitions [3]

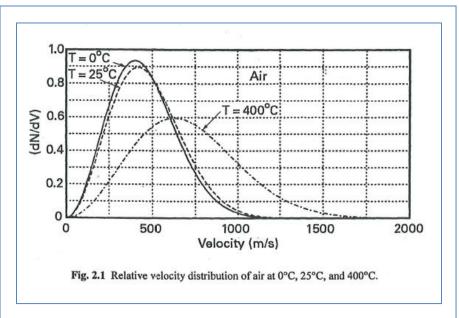
How can conductances be calculated?
How does the dimension, shape, length,
etc... of a vacuum component define its
conductance?

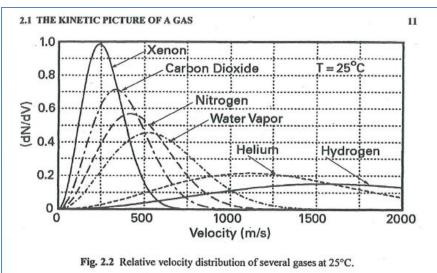
- We need to recall some concepts of kinetic theory of gases:
- The Maxwell-Boltzmann velocity distribution defines an ensemble of ${\cal N}$ molecules of given mass ${\it m}$ and temperature ${\cal T}$ as

$$\frac{dn}{v} = \frac{2N}{\pi^{1/2}} \left(\frac{m}{2kT}\right)^{3/2} v^2 e^{-m \cdot v^2/(2 \cdot k_B \cdot T)}$$

... with n the molecular density, and k_b as before.

• The shape of this distribution for air at different temperatures, and for different gases at 25°C are shown on the right:





Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Units and Definitions [3]

 The kinetic theory of gases determines the <u>mean velocity</u>, <u>most probable</u> <u>velocity</u>, and <u>rms velocity</u> as

$$c_{mean} = \sqrt{\frac{8RT}{\pi \cdot M}}$$

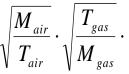
$$c_{mp} = \sqrt{\frac{2RT}{M}}$$

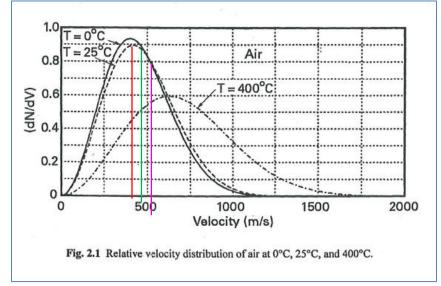
$$c_{rms} = \sqrt{\frac{3RT}{M}}$$

... with R and T as before. Therefore, $c_{mp} < c_{mean} < c_{rms}$. For air at 25°C these values are:

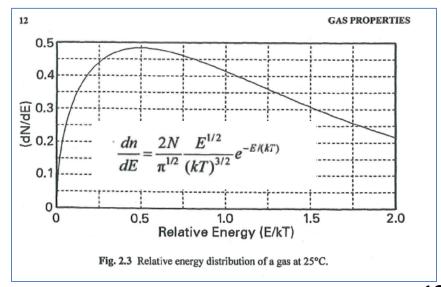
> c_{mp} = 413 m/s c_{mean} = 467 m/s c_{rms} = 506 m/s

For a gas with different m and T, these values scale as \sqrt{M}





The energy distribution of the gas is



Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Transmission probability

•Within the kinetic theory of gases, it can be shown that the volumetric flow rate passing through an infinitely thin hole of surface area A between two volumes is given by $q = A \cdot \frac{\mathcal{C}_{rms}}{A}$

... and by the analogy with the second basic equation we get that the conductance of this thin hole is

$$c = A \cdot \frac{c_{rms}}{4}$$

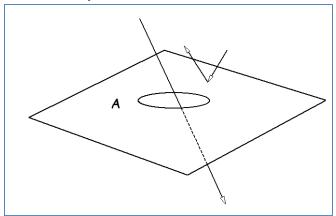
For holes which are not of zerothickness, a "reduction" factor k, 0 < k < 1, can be defined. K is called <u>transmission probability</u>, and can be visualized as the effect of the "side wall" generated by the thickness.

It depends in a complicated way from the shape of the hole.

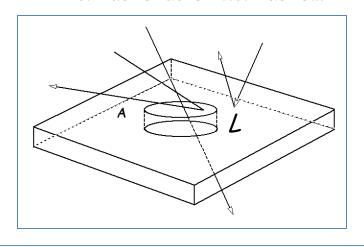
So, in general, for a hole of area A across a wall of thickness L

$$c(A, L) = A \cdot \frac{c_{rms}}{4} \cdot k(A, L)$$

Zero-thickness vs finite-thickness aperture in a wall...



... the transmission probability decreases as L increases...



Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Transmission probability

- •Only for few simple cross-sections of the hole, an analytic expression of k(A,L) exists.
- For arbitrary shapes, numerical integration of an integro-differential equation must be carried out

7. Clausing's investigation of the transmission probability of a tube

Clausing 25-34 calculated the probability W for a tube of circular cross-section

$$W = \int_{0}^{L} W_{SR}(x) \cdot w(x) dx + W_{ss}(L)$$
 (27)

where w(x) is given by an integral equation

$$w(x) = \int_{0}^{L} W_{RR}(\xi - x) d\xi . w(\xi) + W_{RS}(L - x)$$
 (28)

down w(x) in the case of a circular tube:

$$w(x) = \frac{1}{4R} \int_{0}^{L} \left\{ 2 + \frac{(\xi - x)^{3}}{[(\xi - x)^{2} + 4R^{2}]^{\frac{3}{2}}} - \frac{3(\xi - x)}{[(\xi - x)^{2} + 4R^{2}]^{\frac{1}{2}}} \right\}$$

$$w(\xi) d\xi + \frac{1}{4R} \left\{ [(\overline{L - x})^{2} + 4R^{2}]^{\frac{1}{2}} + \frac{(L - x)^{2}}{[(L - x)^{2} + 4R^{2}]^{\frac{1}{2}}} - 2(L - x) \right\}$$

$$(29)$$

(ref. W. Steckelmacher, Vacuum 16 (1966) p561-584)

Where W_{SR} , W_{SS} , W_{RR} and W_{RS} are appropriate functions of R and relate to probabilities of the molecular passage and emittance of molecules (assuming a cosine law of emission) from different parts of the tube wall. Clausing also showed that the function w(x) was related to the impact density g(x) for molecules impinging on the walls of the tube, where x is measured along the tube length. Defining the relative impact

density $h(x) = \frac{g(x)}{N_0}$ he proved the identity

$$h(x) \equiv w(L - x) \tag{30}$$

This proof depends on the principle of detailed balancing according to which for each direction and velocity the number of emitted molecules is equal to the number adsorbed (see also Clausing²⁷).

In trying to solve the integral equation Clausing $^{32-34}$ assumes that for $\frac{R}{L}$ large (\geqslant 1) a good solution is given by

$$w(x) = \alpha + \frac{1 - 2\alpha}{L} \cdot x \tag{31}$$

with α =const. Substitution of this in the integral actually gave an expression for α which may be written in the form;

$$\alpha = \frac{\left[u(u^2+1)^{\frac{1}{2}} - u^2\right] - \left[v(v^2+1)^{\frac{1}{2}} - v^2\right]}{\frac{u(2v^2+1)^{\frac{1}{2}}}{(v^2+1)^{\frac{1}{2}}} - \frac{v(2u^2+1) - u}{(u^2+1)^{\frac{1}{2}}}\right] = \alpha \left(\frac{R}{L}, \frac{x}{L}\right)$$
(32)

where
$$u = (L-x)/2R$$
 and $v = x/2R$, ie $u = (L/R) - v$ (34)

He then selected α such that $W = \frac{8R}{3L}$ for long tubes, ie assuming

the Knudsen formula for long tubes. He showed that a good approximation was obtained for short tubes when $L \leq 4R$ by taking

$$\alpha = \frac{\sqrt{L^2 + 4R^2 - L}}{4R^2}$$
 (35), and when $L > 4R$, $\alpha = \alpha \left(\frac{R}{L}, \frac{x}{L}\right)$ (35)

given by the above formula for $\alpha\left(\frac{R}{L},\frac{x}{L}\right)$ but with

$$x/L = 2R\sqrt{7}/(3L + 2R\sqrt{7})$$
 ie $u = \frac{L\sqrt{7}}{3L + 2R\sqrt{7}}$ (36)

With this choice (he points out, it is one of many), for very small R/L

$$\alpha \rightarrow \frac{4R}{3L}$$
 so that $W \rightarrow \frac{8R}{3L}$.

With these approximations Clausing then calculated W for a range of values of L/R, which he tabulated, and these Clausing probability factors formed the basis for flow calculations in tubes for more than 20 years.

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Sum of Conductances

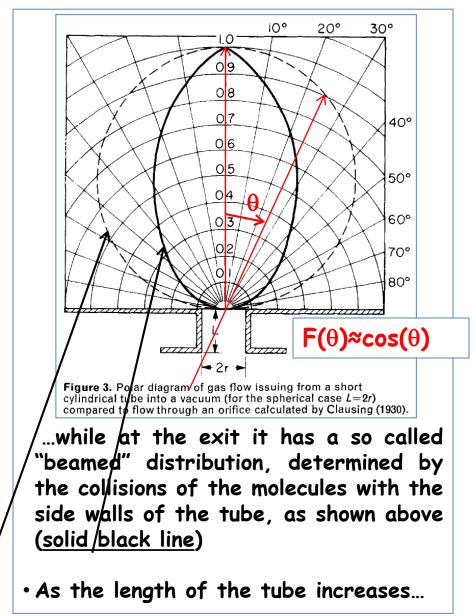
- Keeping in mind the interpretation of the conductance as the reciprocal of a resistance in an electric circuit, we may be tempted to use "summation rules" similar to those used for series and parallel connection of two resistors.
- •It turns out that these rules are not so far off, they give meaningful results provided some "correction factors" are introduced

$$C = C_1 + C_2 \quad \text{parallel}$$

$$\frac{1}{C} = \frac{1}{C_1} + \frac{1}{C_2} \quad \text{series}$$

and they can be extended to more elements by adding them up.

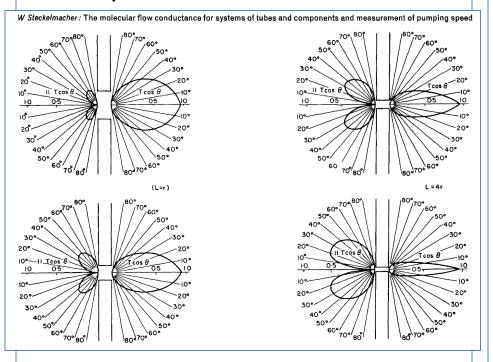
- The correction factor takes into account also the fact that the flow of the gas as it enters the tube "develops" a varying angular distribution as it moves along it, even for a constant section.
- At the entrance, the gas crosses the aperture with a "cosine distribution"



15

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Molecular Beaming Effect

... so does the beaming, and the forward- and backward-emitted molecules become more and more skewed, as shown here...



- The transmission probability of <u>any</u> shape can be calculated with arbitrary precision by using the *Test-Particle Montecarlo method* (TPMC).
- The TPMC generates "random" molecules according to the cosine distribution...

- ... at the entrance of the tube, and then follows their traces until they reach the exit of the tube.
- Time is not a factor, and residence time on the walls is therefore not an issue.
- Each collision with the walls is followed by a random emission following, again, the cosine distribution...
- ... this is repeated a very large number of times, in order to reduce the statistical scattering and apply the large number theorem.
- The same method can be applied not only to tubes but also to three-dimensional, arbitrary components, i.e. "models" of any vacuum system.
- •In this case, pumps are simulated by assigning "sticking coefficients" to the surfaces representing their inlet flange.
- The sticking coefficient is nothing else than the probability that a molecule... 16

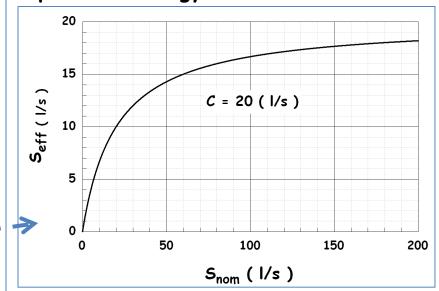
Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Effective Pumping Speed

- ... entering the inlet flange gets pumped, i.e. removed from the system.
- The equivalent sticking coefficient s of a pump of S [I/s] represented by an opening of A [cm²] is given by

$$s = \frac{S}{A \cdot \frac{c_{rms}}{4}}$$

- ... i.e. it is the ratio between the given pumping speed and the conductance of the zero-thickness hole having the same surface area of the opening A.
- The "interchangeability" of the concept of conductance and pumping speed, both customarily defined by the units of [l/s] (or $[m^3/s]$, or $[m^3/h]$), suggests that if a pump of nominal speed S_{nom} [l/s] is connected to a volume V via a tube of conductance C, the <u>effective pumping</u> <u>speed</u> of the pump will be given by the relationship 1 1

- From this simple equation it is clear that it doesn't pay to increase the installed pumping speed much more than the conductance C, which therefore sets a limit to the achievable effective pumping speed.
- This has <u>severe implications</u> for accelerators, as they typically have vacuum chambers with a tubular shape: they are "<u>conductance-limited systems</u>", and as such need a specific strategy to deal with them



Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Transmission Probability and Analytical Formulas

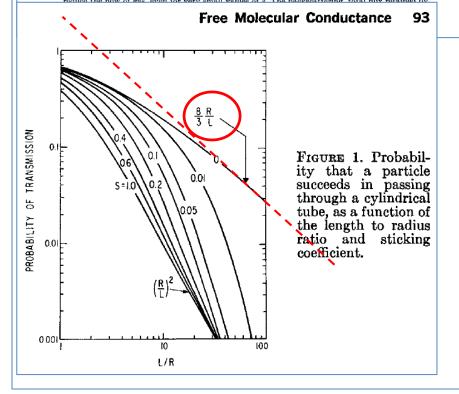
• The transmission probability of tubes has been calculated many times. This paper (J.Vac.Sci.Technol. 3(3) 1965 p92-95)

Free Molecular Conductance of a Cylindrical Tube with Wall Sorption

Craig G. Smith and Gerhard Lewin

Plasma Physics Laboratory, Princeton University, Princeton, New Jersey (Received 26 October 1965)

A Monte Carlo method was used to calculate the probability that a molecule passes through a cylindrical tube with wall sorption. This probability is presented as a function of the ratio of length to radius and the sticking coefficient s of the wall. For s = 0, the results confirm those of Clausing for the conductance of a tube of finite length. For $s \neq 0$, wall pumping can greatly radius the flow of rate over the flow of rate over



... gives us a way to calculate the conductance of a cylindrical tube of any length to radius ratio L/R >0.001:

$$C_{transm}(l/s) = A_{inlet}(cm^2) \cdot 11.77(l/s/cm^2) \cdot P_{transm}$$

- ... where P_{transm} is the transmission probability of the tube, as read on the graph and 11.77 is the "usual" kinetic factor of a mass 28 gas at 20°C.
- •Other authors have given approximate equations for the calculation of $C_{\rm transm}$, namely Dushman (1922), prior to the advent of modern computers

$$C_{transm}(l/s) = 12.4 \frac{D^3/L}{1+4 \cdot \frac{D}{3 \cdot L}}$$

... with D and L in m.

- •We can derive this equation by considering a tube as two conductances in series: C_A , the aperture of the tube followed by the tube itself, C_B .
- By using the summation rule for....

Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators

Dushman's Formula for Tubes (see P.Chiggiato's lecture for more refined models/formula, like his (21))

... 2 conductances in series...

$$\frac{1}{C} = \frac{1}{C_A} + \frac{1}{C_B}$$

... we obtain:

$$C_A = 9.3 \cdot D^3$$
 and $C_B = 12.4 \cdot D^3 / L$

... with D and L in cm. Substituting above...

$$C = \frac{C_A \cdot C_B}{C_A + C_B} = \frac{12.4 \cdot D^3 / L}{1 + 4 \cdot D / (3 \cdot L)}$$

Beware: the error can be large!

- Exercise: 1) estimate the conductance of a tube of D=10 [cm] and L=50 [cm] by using the transmission probability concept and compare it to the one obtained using Dushman's formula.
- 2) Repeat for a tube with L=500 [cm].
- 3) Calculate the relative error.

- This fundamental conductance limitation has profound effects on the design of the pumping system: the location, number and size of the pumps must be decided on the merit of minimizing the average pressure seen by the beam(s).
- The process is carried out in several steps: first a "back of the envelope" calculation with evenly spaced pumps, followed by a number of iterations where the position of the pumps and eventually their individual size (speed) are customized.
- Step one resembles to this: a cross-section common to all magnetic elements is chosen, i.e. one which fits inside all magnets (dipoles, quadrupoles, sextupoles, etc...): this determines a <u>specific conductance</u> for the vacuum chamber $c_{\rm spec}$ ($l \cdot m/s$), by means of, for instance, the <u>transmission probability</u> method.

•We then consider a chamber of uniform cross-section, of specific surface A [cm²/m], specific outgassing rate of q [l/s/cm²], with equal pumps (pumping speed S [l/s] each) evenly spaced at a distance L. The following equations can be written:

$$Q(x) = -c \frac{dP(x)}{dx}$$
$$\frac{dQ(x)}{dx} = Aq$$

...which can be combined into

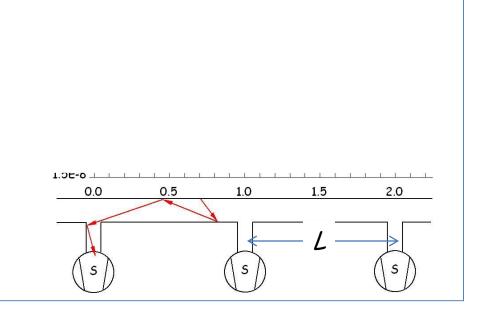
$$c\frac{d^2P}{dx^2} = -Aq$$

... with boundary conditions

$$\begin{cases} \frac{dP}{dx}(x = L/2) = 0\\ P(x = 0) = AqL/S \end{cases}$$

... to obtain the final result

$$P(x) = \frac{Aq}{2c} (Lx - x^2) + \frac{AqL}{S}$$



Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators

Pressure Profiles and More...

• From this equation for the pressure profile, we derive three interesting quantities: the average pressure, the peak pressure, and the effective pumping speed as:

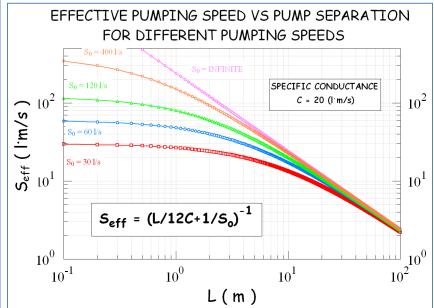
$$P_{AVERAGE} = \frac{1}{L} \int_{0}^{L} P(x) dx = AqL(\frac{L}{12c} + \frac{1}{S}) = AqL(1/S_{EFF})$$

$$P_{MAX} = AqL(\frac{1}{8c} + \frac{1}{S})$$

$$S_{EFF} = (\frac{L}{12c} + \frac{1}{S})^{-1}$$

- •From the 1st and 3rd ones we see that once the specific conductance is chosen (determined by the size of the magnets, and the optics of the machine), how low the average pressure seen by the beam can be is limited by the effective pumping speed, which in turn depends strongly on c.
- The following graph shows an example of this: for c=20 [$l\cdot m/s$] and different nominal pumping speeds for the pumps, the graphs show how S_{eff} would change.

- This, in turn, determines the average... <u>pump spacing</u>, and ultimately the <u>number of pumps</u>.
- •Summarizing: in one simple step, with a simple model, one can get an estimate of the size of the vacuum chamber, the number and type of pumps, and from this, roughly, a first estimate of the capital costs for the vacuum system of the machine. Not bad!



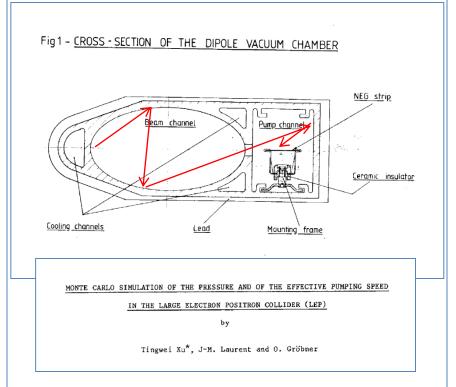
Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Pressure Profiles and More...

- *From the previous analysis it is clear that there may be cases when either because of the size of the machine or the dimensions of (some of its) vacuum chambers, the number of pumps which would be necessary in order to obtain a sufficiently low pressure could be too large, i.e. impose technical and cost issues. One example of this was the LEP accelerator, which was 27 km-long, and would have needed thousands of pumps, based on the analysis we've carried out so far.
- So, what to do in this case? Change many pumps into one continuous pump, i.e. implement distributed pumping.
- •In this case if S_{dist} is the distributed pumping speed, its units are [l/s/m], the equations above become:

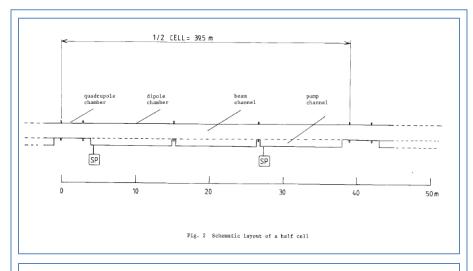
$$P_{AVG} = Aq / S_{EFF}$$

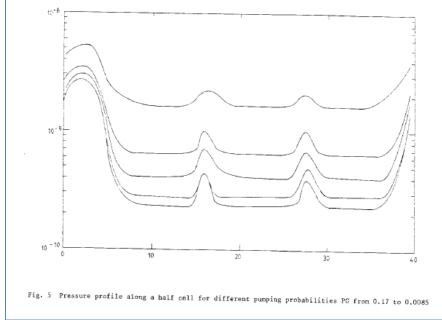
$$P_{MAX} = P_{AVG} \qquad S_{EFF} = S_{dist} \cdot L$$

- We obtain a flat, <u>constant</u>, pressure profile.
- The distributed pressure profile in LEP had been obtained by inserting a NEG-strip along an ante-chamber, running parallel to the beam chamber, and connected by small elliptical slots:



Gas Flow, Conductance, Pressure Profile: Fundamentals of Vacuum Technology for Accelerators Pressure Profiles and More...





Effect on pressure profile of S_{dist}

Exercise: knowing that one metre of NEG-strip and the pumping slots provide approximately 294 [1/s/m] at the beam chamber, derive the equivalent number of lumped pumps of 500 [1/s] which would have been necessary in order to get the same average pressure.

Input data:

```
- C_{\text{spec}}(\text{LEP}) = 100 [l \cdot \text{m/s}]

- S_{\text{dist}}(\text{LEP}) = 294 [l/\text{s/m}]

- A_{\text{LEP}} = 3,200[\text{cm}^2/\text{m}];

- q = 3.0\text{E}-11 [\text{mbar*l/s/cm2}]
```

- Exercise: the SPS transfer line has a vacuum pipe of 60 [mm] diameter, and the distance L between pumps is ~ 60 [m]. The pumping speed of the ion-pumps installed on it is ~ 15 [l/s] at the pipe. Assuming a thermal outgassing rate q=3E-11 [mbar·l/s/cm²] calculate:
 - 1) P_{max} , P_{min} , P_{avg} , in [mbar]
 - 2) S_{eff} , in [l/s]

Conclusions:

- During this short tutorial we have discovered some important concepts and equations related to the field of vacuum for particle accelerators.
- •We have seen that one limiting factor of accelerators is the fact that they always have long tubular chambers, which are inherently *conductance limited*.
- •We have also seen some basic equations of vacuum, namely the P=Q/S which allows a very first glimpse at the level of pumping speed S which will be necessary to implement on the accelerator in order to get rid of the outgassing Q, which will depend qualitatively and quantitatively on the type of accelerator (see P.Chiggiato's lessons on outgassing and synchrotron radiation, this school).
- •Links between the thermodynamic properties of gases and the technical specification of pumps (their pumping speed) as been given: the link is via the <u>equivalent sticking coefficient</u> which can be attributed to the inlet of the pump.
- •One simple model of accelerator vacuum system, having uniform desorption, evenly spaced pumps of equal speed has allowed us to derive some preliminary but powerful equations relating the *pressure* to the *conductance* to the *effective pumping speed*, and ultimately giving us a ballpark estimate about the number of pumps which will be needed.
- •Finally, an example of a real, now dismantled, accelerator has been discussed (LEP), and the advantages of <u>distributed pumping</u> vs <u>lumped pumping</u> detailed.

References

(other than those given on the slides):

- P. Chiggiato, this school, and previous editions
- R. Kersevan, M. Ady: http://test-molflow.web.cern.ch/
 Link to sample files discussed during the talk:
 https://dl.dropboxusercontent.com/u/104842596/zipped.7z
- •Y. Li et al.: "Vacuum Science and Technology for Accelerator Vacuum Systems", U.S. Particle Accelerator School, Course Materials Duke University January 2013; http://uspas.fnal.gov/materials/13Duke/Duke_VacuumScience.shtml

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